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Application of the Theory of Dispersion Forces to the Dewetting of Polymer Films^{*}

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Abstract: The theory of Dzyaloshinskii, Lifshitz, and Pitaevskii (DLP) is applied to investigate the effects of dispersion forces in the dewetting of polymer films in the system of air, polymer, silicon oxide and silicon. The second derivate of the free energy, wavelength and growth rate are calculated. The results show that the coating can modulate the wettability of its substrate and the retarded effects can be significant sometimes. They should be taken into account to deal with the dewetting instability of the polymer films. **Key words:** dispersion forces; dewetting; retarded effects; wavelength; growth rate

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1 Introduction

Dewetting is a phenomenon in which thin liquid films on solid substrates break up into liquid droplets. Because of the widespread usage of organic films, much effort has been put into understanding dewetting phenomenon both experimentally and theoretically in recent years^[11]. Owing to the immense complexity of the involved mechanisms, there is yet no general agreement reached concerning the underlying physics of dewetting and structure formation at interface. On a theoretical basis, two mechanisms are possible, according to whether the film is unstable or metastable^[7]. With unstable films, rupturing occurs spontaneously via a spinodal mechanism. In metastable films, rupturing starts from nucleation of domain bubble, a process called heterogeneous nucleation. The distinction is thermodynamics in character, determined by the free energy per unit area of the film F(L). The shape of F(L), as a function of film thickness, L, contains crucial information about the stability of a thin film. The first and second derivatives of the potential yield the disjoining pressure and the spinodal parameter, with the latter containing information on the stability and initial evolution kinetics of a flat film. If F'(L) is negative, the film is unstable; otherwise, the film is either stable or metastable. From the shape of the potential of an unstable film one can infer the upper and lower stable thickness by means of Maxwell constructions and also semi-quantitatively estimate the shape of a stable droplet. For apolar polymer films on a substrate, the most widely adopted form assumes the nonretarded Lifshitz van der Waals (LW) interactions and it has almost exclusively been treated as noretarded, meaning that they work instantaneously through the media separating the interaction surfaces, namely, $F(L) = -A/12\pi L^2$, where A is the Hamaker constants. However, this

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form of F(L) is valid only for a very small film thickness less then 5 nm. Otherwise, retardation effects have to be considered ^[12-15].

2 Theory

In this paper, we study a model system of air, polymer, silicon oxide, and silicon (hereafter referred to as the Air/PS/SiO/Si system), which turn out to account for the effects of dispersion forces in polymer dewetting. The second derivatives of the free energy, wavelength and growth rate are calculated to investigate the effects of the coating on the substrate and the retarded effects. Our studies focus on the calculation of the excess Helmholtz free energy of the polymer film of thickness at the interface between two other media. Because of the inherent many-body nature of such interactions in condense matter, the dispersion forces effects are most conveniently treated by considering all phase as isotropic continuous media characterized by frequency-dependent dielectric functions. This is the approach taken by Dzyaloshinskii, Lifshitz, and Pitaevskii (DLP) that includes the temperature and retardation effects^[16]. The main result is an expression for the excess free energy per unit area of a film of a given medium between two other media. The general scheme for calculating the LW free energy F in layered geometry is^[17-18]

$$F = k_B T \sum_{n=0}^{\infty} \int_0^\infty \ln W(\vec{q}, \omega) = i \xi_n \frac{dq_x dq_y}{(2\pi)^2}, \qquad (1)$$

The function $W(\vec{q}, \omega)$ determines the dispersion relations of the electromagnetic normal modes that satisfy the corresponding boundary conditions and field equations. q_x and q_y are the components of the wave vector which are parallel to the surfaces. The prime on the sum indicates that the n=0 term is halved. $\xi_y = (2\pi k_B T / \hbar) n, k_B$, \hbar and T have their usual meaning. By assigning the energy of a harmonic oscillator to each allow ed electromagnetic mode and solving M axwell's equations with boundary conditions, we can get the excess free energy per unit area of the polystyrene film of thickness L in the layered geometry,

$$F(L) = \frac{k_B T}{8\pi L^2} \sum_{n=0}^{\infty} \int_{r_n}^{\infty} x \ln[g(R)g(\overrightarrow{R})] dx, \qquad (2)$$

where: $g(R) = 1 - \left(\frac{R(x_i, x_w)R(x_h, x_w) + R(x_i, x_w)R(x_x, x_h)R(x_x, x_h)e^{-2x_h d/L}}{1 - R(x_v, x_h)R(x_w, x_h)e^{-2x_h d/L}}e^{-x}; R(x_j, x_k) = \frac{x_j - x_k}{x_j + x_k};$

 $\overrightarrow{R}(x_{j}, x_{k}) = \frac{x_{j} \mathcal{E}_{k} - x_{k} \mathcal{E}_{j}}{x_{k} \mathcal{E}_{k} + x_{k} \mathcal{E}_{j}}; x_{w} = x; x_{k} = \left[x^{2} + r_{n}^{2}(\mathfrak{E}/\mathfrak{E}_{w})\right]^{1/2}(k = v, h, i), \text{ and the material } (v, h, w, i) \text{ (cor-$

responding to silicon, silicon oxide, polystyrene and air) dielectric functions are evaluated at the sequence of imaginary frequencies $i\xi_n$. The lower limit of integration is $r_n = 2L(\varepsilon_e)^{1/2}\xi_e/c$. If the silicon is clean, i. e., the layer of silicon oxide is cancelled, equation (2) reduces to the following form,

$$F(L) = \frac{k_B T}{8\pi L^2} \sum_{n=0}^{\infty} \int_{r_n}^{\infty} x \left[\ln\left(1 - \frac{(x - x_i)(x - x_v)}{(x + x_i)(x + x_v)} e^{-x}\right) + \ln\left(1 - \frac{(\varepsilon_{i} x - \varepsilon_{e} x_i)(\varepsilon_{i} - \varepsilon_{e} x_i)}{(\varepsilon_{i} x + \varepsilon_{e} x_i)(\varepsilon_{i} - \varepsilon_{e} x_i)} e^{-x}\right) \right] dx.$$
(3)

If the retardation effect is not included, an approximation to equation (3) can be written as

$$F(L) = \frac{k_B T}{8\pi L^2} \sum_{n=0}^{\infty} \int_0^\infty x [\ln(1 - \frac{(\aleph - \aleph_e)(\aleph - \aleph_e x)}{(\aleph + \aleph_e)(\aleph + \aleph_e)} e^{-x})] dx.$$
(4)

The dielectric functions required in the integral, $\mathfrak{C}(i\xi)$, is the analytic continuation of the material dielectric function $\mathfrak{C}(\omega)$ to imaginary frequencies. They can be easily generated from the fitting of the dielectric response of the material to a damped-oscillator model of the form

$$\mathfrak{E}(\omega) = 1 + \sum_{j} \frac{f_{j}}{e_{j}^{2} - i\hbar\omega g_{j} - (\hbar\omega)^{2}},$$
(5)

where e_i , f_i and g_i are fitting parameters.

In principle, DLP theory is applicable to any bodies at any temperature, independent of their molecular nature. Since the theory follows from the exact equations of the electromagnetic field, it automatically

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takes account of retardation effects. Equation (2) assumes implicitly that the medium is isotropic. The LW result for materials with anisotropic polarizability functions had been worked $out^{[19]}$. We neglect anisotropy of the materials polarizability in this work for it seems to be small in our model system.

3 Results and Discussions





The dielectric functions come from several different sources. For ice, water and polystyrene, we have used the fits to the dielectric data determined by Parsegian and Weiss^[20]. Data for silicon based on a single band model was obtained from Sabisky and Anderson^[21] and the dielectric function for silicon oxide was taken from Hough and White that were based on a double band model^[18]. In order to check that our numerical procedure gave correct results, we calculated the free energy of air water-ice system. The free energy per unit area as a function

of film thickness L is shown in figure 1. We readily find that our results agree well with that of Michael Elbaum and M. Schick, which a minimum was obtained in the surface free energy corresponding to a rather thick film of water, 3.6 nm^[14].

The effective interface potential of the system F(L), or more precisely F''(L), the second derivative of F(L) with respect to the film thickness L, is related to the spontaneous rupture. It is readily shown that the spinodal instability can take place only if F''(L) is negative. Whenever this is the case, the system is unstable. We show the free energy per unit area of polystyrene F(L) and F''(L) on different types of Si wafers in Figure 2 and Figure 3, respectively. It is found PS films on top of pure, clean Si substrate are stable, but they are unstable on infinitely thick oxide layers. When the thickness of silicon oxide are 2 nm, 5 nm, the sign of F''(L) will change as the film thickness increases as large as 6 nm, 15 nm, respectively; whereas it is still negative when the film thickness becomes 100 nm when the silicon oxide thickness is 106 nm. These results show the stability of the PS films can be modulated by the variation of the oxide. From the Figure 2, we can see that excess free energy of air/PS/SiO system is almost the same as the air/PS/SiO/Si in which silicon oxide thickness is 106 nm. It can be infered that the Si substrate has little influence on the total interaction in this case.



Fig. 2 The Free Energy per Unit Area of Polystyrene on Different Types of Si Wafers in Air/ PS/ SiO/ Si System



Fig. 3 The Second Derivative of the Free Energy Per Unit Area of Polystyrene on Different types of Si Wafers in Air/ PS/ SiO/ Si System



U sing the mean field approach and simplifying to linear calculations, $Vrij^{[22]}$ and other^[23-25] have shown that stability would drive the system into exponentially growing mode which had wavelength $\lambda_n = (8\pi^2 \forall F''(L))^{1/2}$ and growth rate $\Gamma_m = L^3 F''$ $(L)^2/(12\mu_Y)$, where Y and μ are the liquid surface tension and viscosity, respectively. The wavelengths for three kinds of Si wafers are shown in Figure 4, respectively. We can see that the influence of silicon oxide layer thickness on the total free energy is comparatively large.

The long range LW interactions in our air/PS/SiO/Si system is made up of three interactions and can be readily obtained by pair wise summation in the microscopic approach of London and Hamak-er^[15-16],

$$F(L) = \frac{A_{\rm sio}}{12\pi L^2} + \frac{A_{\rm sio} - A_{\rm si}}{12\pi (L+D)^2},$$
(5)

where A so and A s indicate the Hamaker constants of air/PS/SiO and air/PS/Si system respectively and D is the thickness of silicon oxide.

In order to check the retardation effects, a comparison is made for the values of the growth rates calculated by using the full (2) and approximate free energy form (5) in Figure 5. It is found that the full results deviate the non-retarded results at a smaller film thickness when the silicon oxide is small. Our study shows that the contribution of the layer of silicon oxide to the total interaction free energy must be important when its thickness is not large enough to screen the substrate and the retarded effect may be important in the instability of polystyrene films sometimes



Fig. 5 The Values of the Growth Rates Calculated by Using the Full and the Approximate form of Free Energy in Air/ PS/ SiO/ Si System

4 Conclusions

In this work, we have applied the DPL theory to investigate the instability of PS films within the framework of the frequency-dependent theory of dispersion forces. It is found that the stability of the film can be tuned by the properties and the variation of the thickness of the coating. As the film thickness increases, we find that the retarded effects can be significant and the full results of free energy must be used to deal with the instability of the PS films. The film instability can only be induced by the defect or thermal nucleation if there is no coating on the substrate. As the coating thickness increases, the film becomes instable. When the coating is as large as about, the film will become unstable, regardless of the substrate.

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应用色散力原理研究高分子薄膜的去湿润现象

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摘 要: 应用 Dzyaloshinskii, Lifshitz, 和 Pitaevskii(DLP) 理论研究了"空气/高分子薄膜/SiO₂/Si⁷体系中色散力对薄膜 表面去湿润的影响,计算了自由能的二阶导数、波长和生长率.研究结果表明:覆盖层可以改变基底的湿润性,延迟效应在 某些情况下起着很重要的作用,在研究去湿润引起的高分子薄膜不稳定时必须考虑延迟效应.

关键词: 色散力; 去湿润; 延迟效应; 波长; 生长率

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